

Docket No.: 50090-306

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Hiroshi TOBIMATSU, et al.

Serial No.:

Group Art Unit:

Filed: July 24, 2001

Examiner:

For: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE HAVING
PASSIVATION FILM AND BUFFER COATING FILM



INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

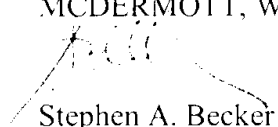
Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Respectfully submitted,

MCDERMOTT, WILL & EMERY


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